



"RESPONSE UNDER 37 CFR 1.116-  
EXPEDITED PROCEDURE EXAMINING  
GROUP 1765"

DOCKET NO: 268844US0PCT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :  
HIROSHI SHIHO, ET AL. : EXAMINER: CHEN, KIN CHAN  
SERIAL NO: 10/529,742 :  
FILED: JANUARY 6, 2006 : GROUP ART UNIT: 1765  
FOR: POLISHING PAD FOR :  
SEMICONDUCTOR WAFER AND  
LAMINATED BODY FOR POLISHING OF  
SEMICONDUCTOR WAFER EQUIPPED  
WITH THE SAME AS WELL AS  
METHOD FOR POLISHING OF  
SEMICONDUCTOR WAFER

REQUEST FOR RECONSIDERATION

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

Responsive to the Office Action of June 8, 2007, Applicants request reconsideration  
in view of the following remarks.

**Remarks** begin on page 2 of this paper.